

*Method And Apparatus For Reducing Substrate Edge
Effects In Electron Lenses*

Inventor(s): Marian Mankos, et al.
Atty Docket No. 10011.001710 (P1100)

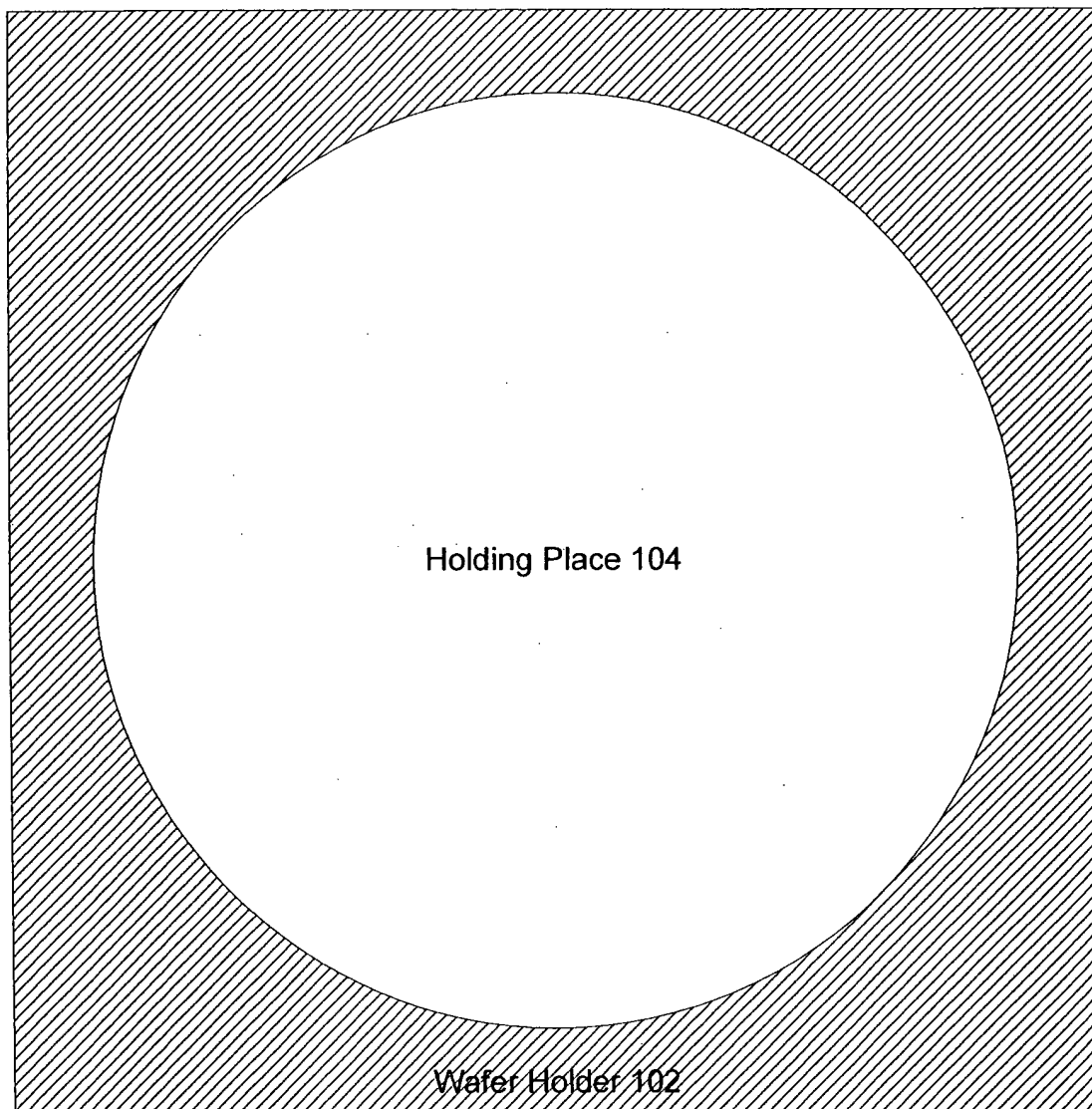


FIG. 1A

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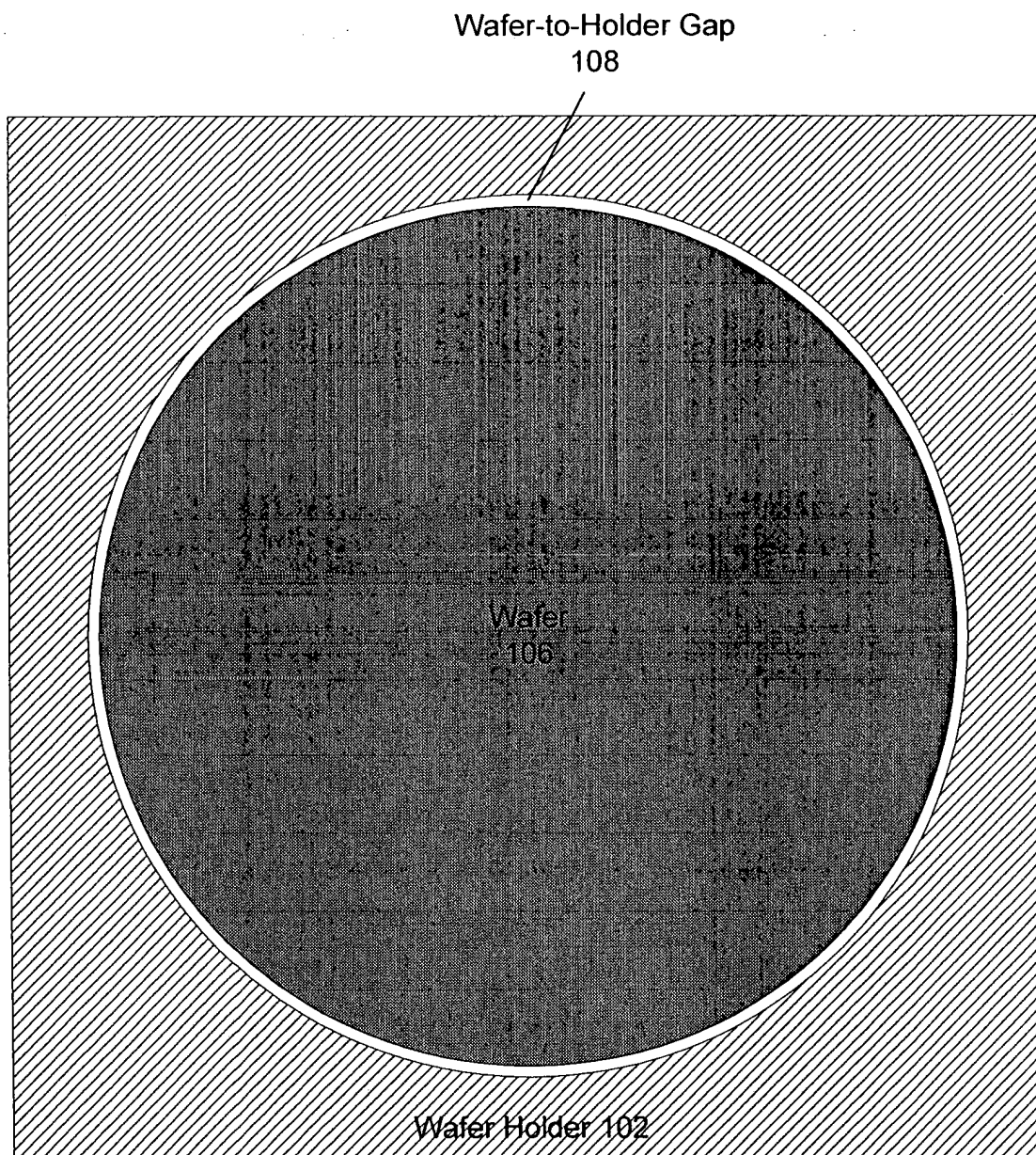


FIG. 1B

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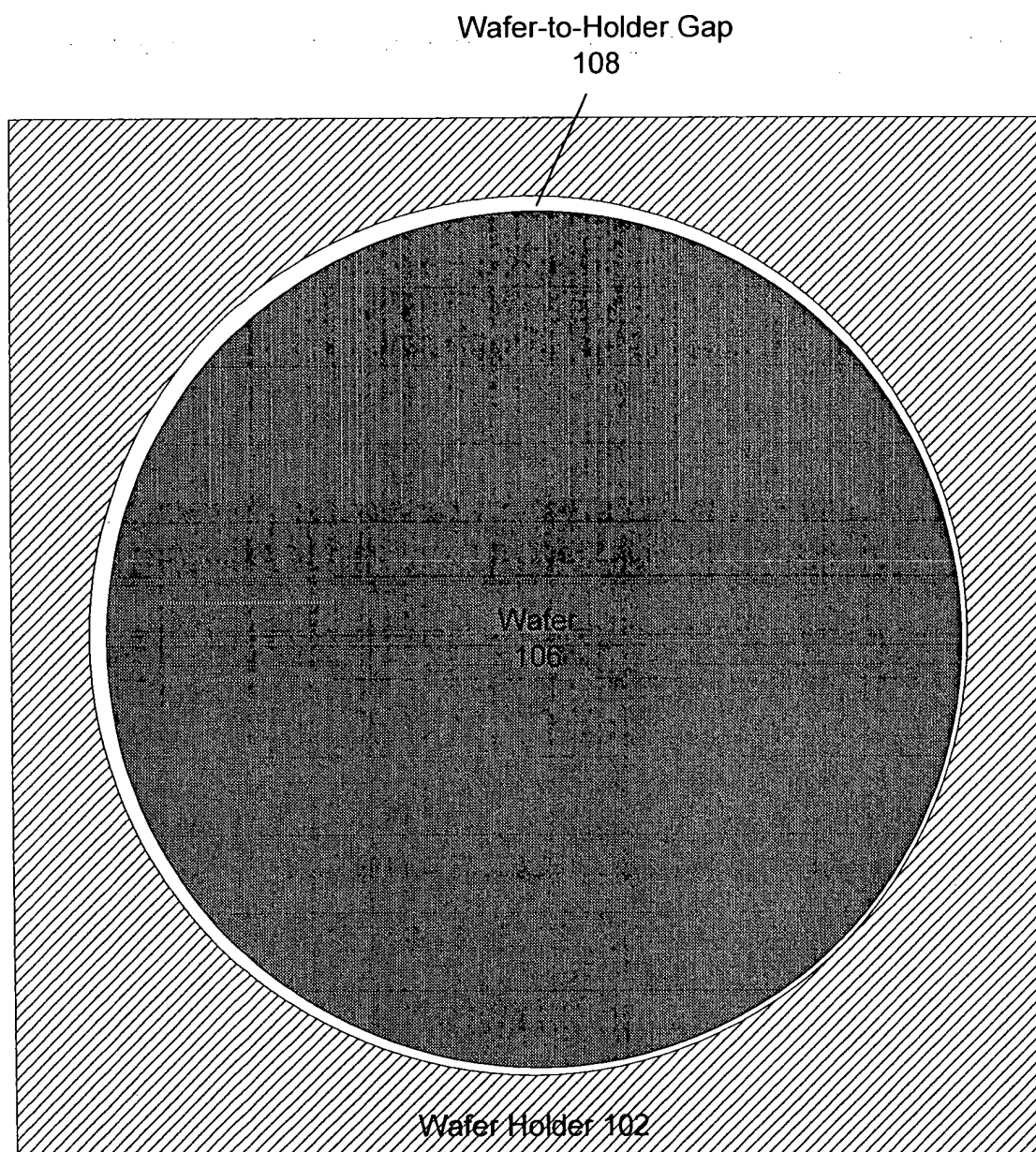


FIG. 1C

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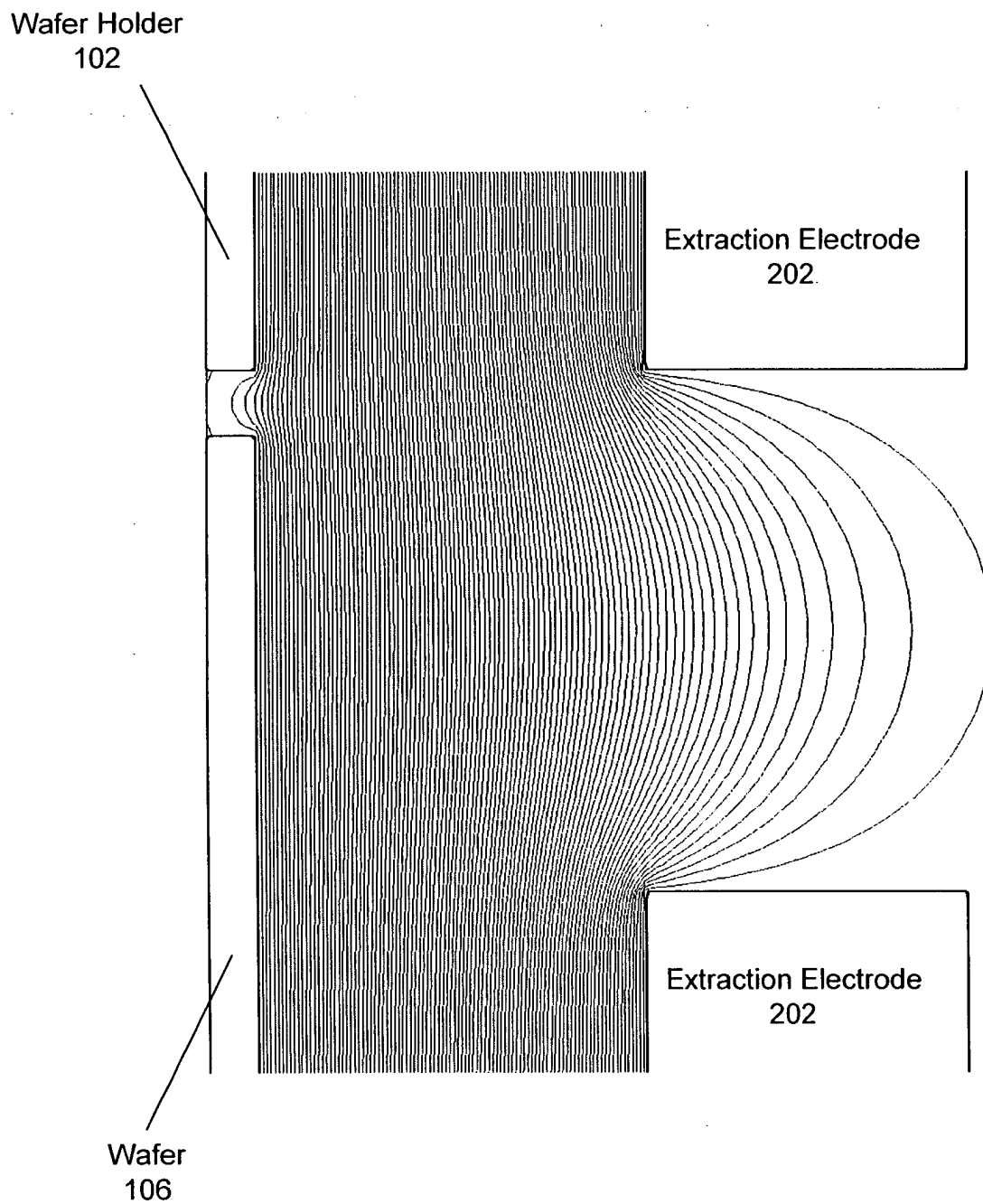


FIG. 2

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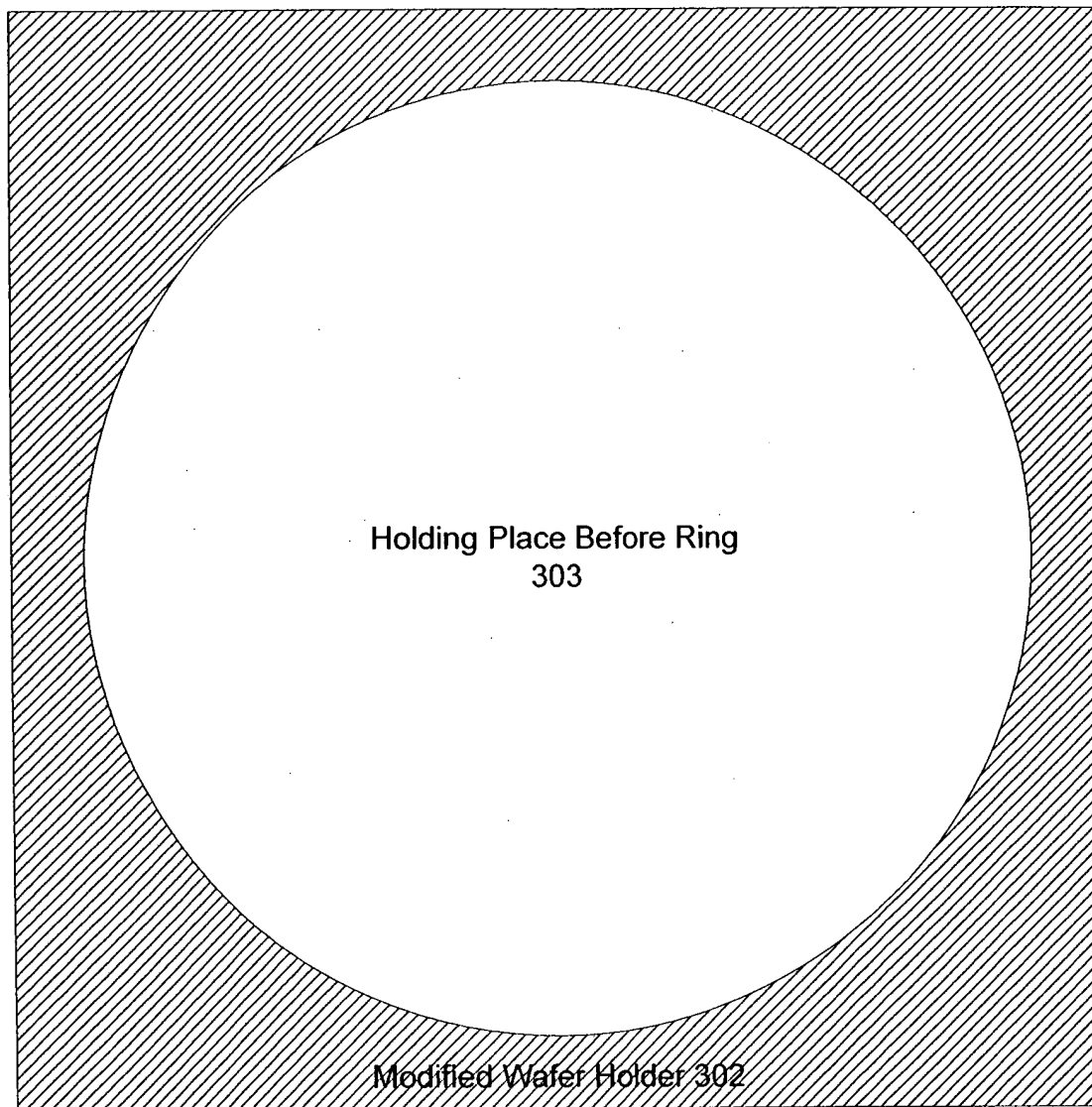


FIG. 3A

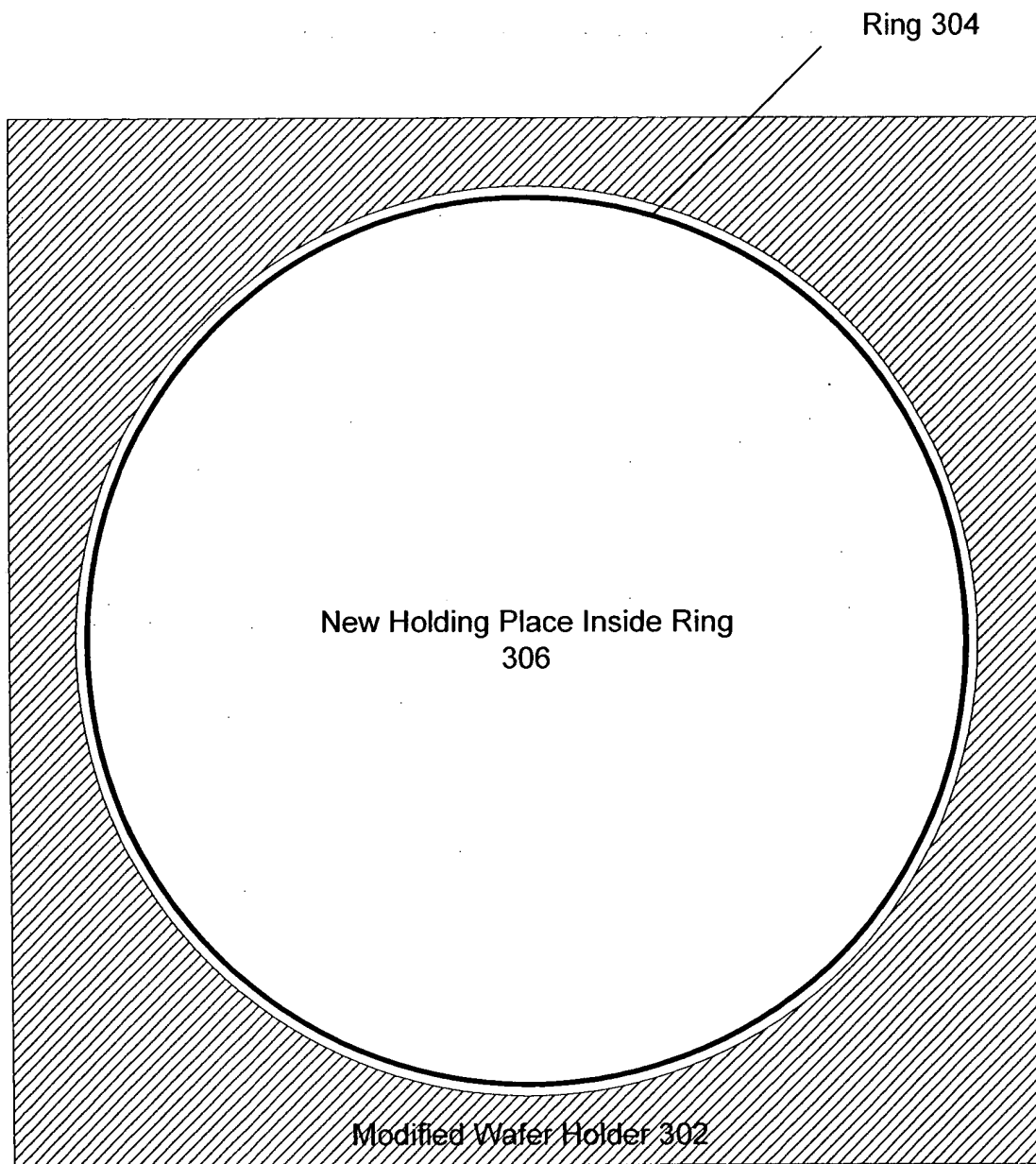


FIG. 3B

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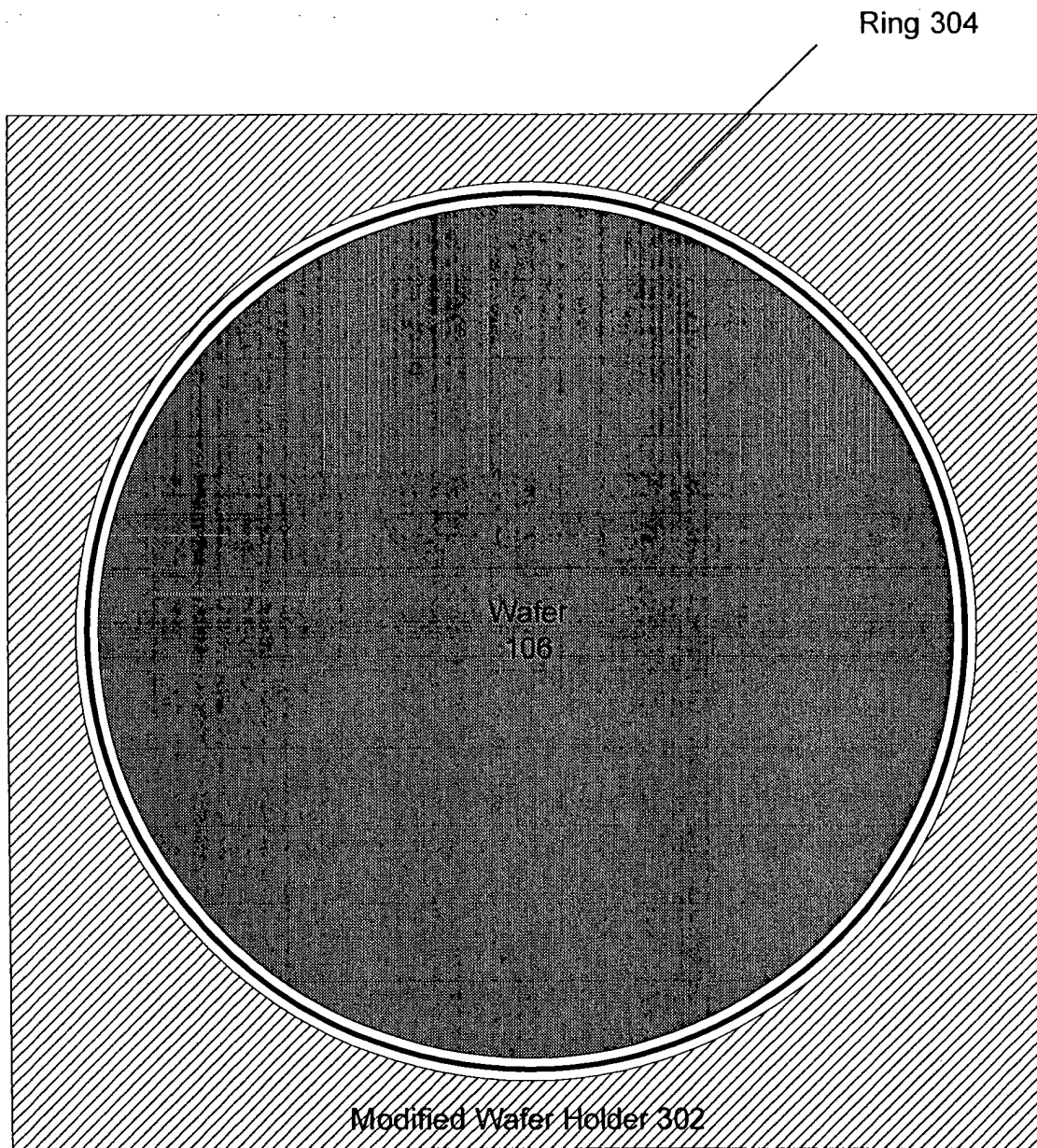


FIG. 3C

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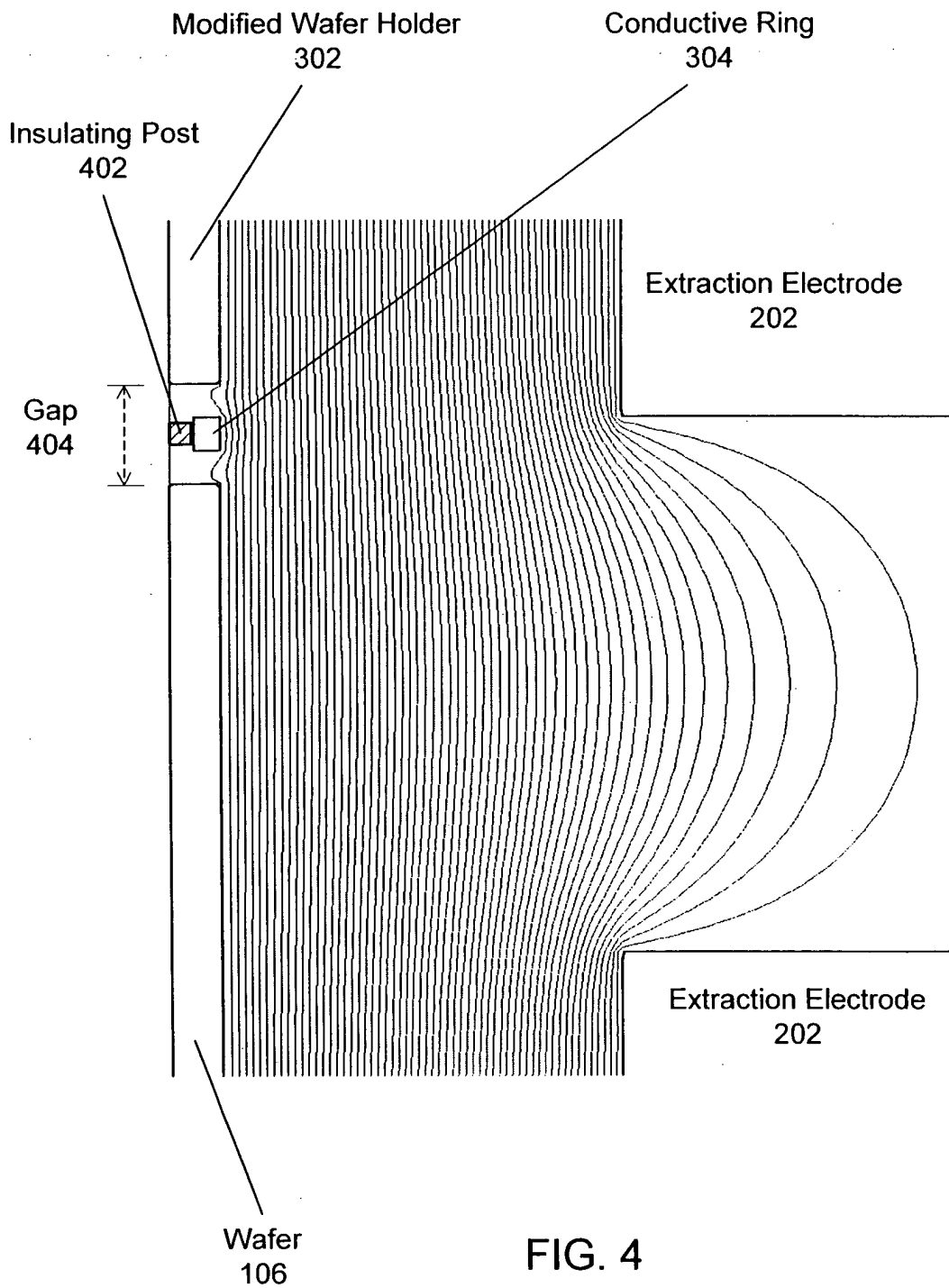


FIG. 4

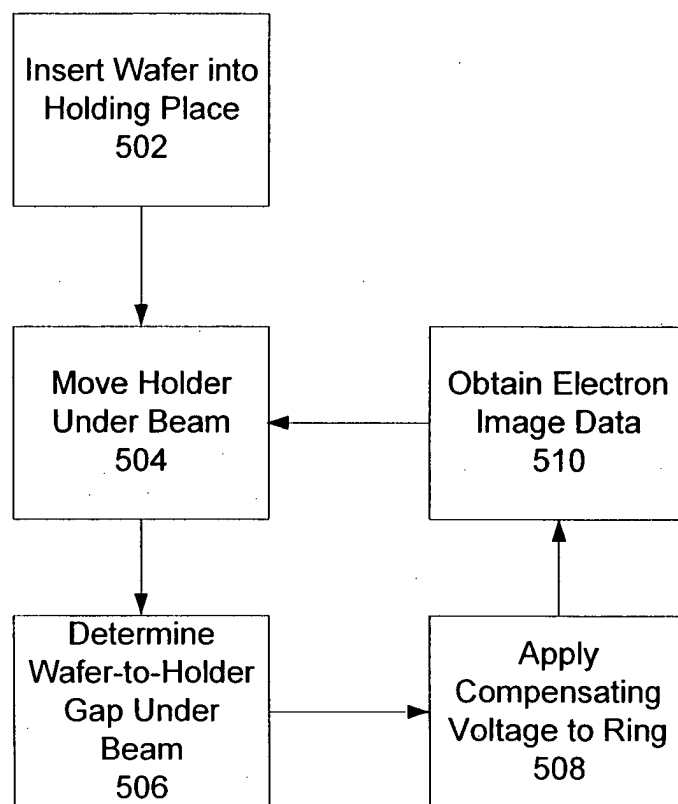


FIG. 5

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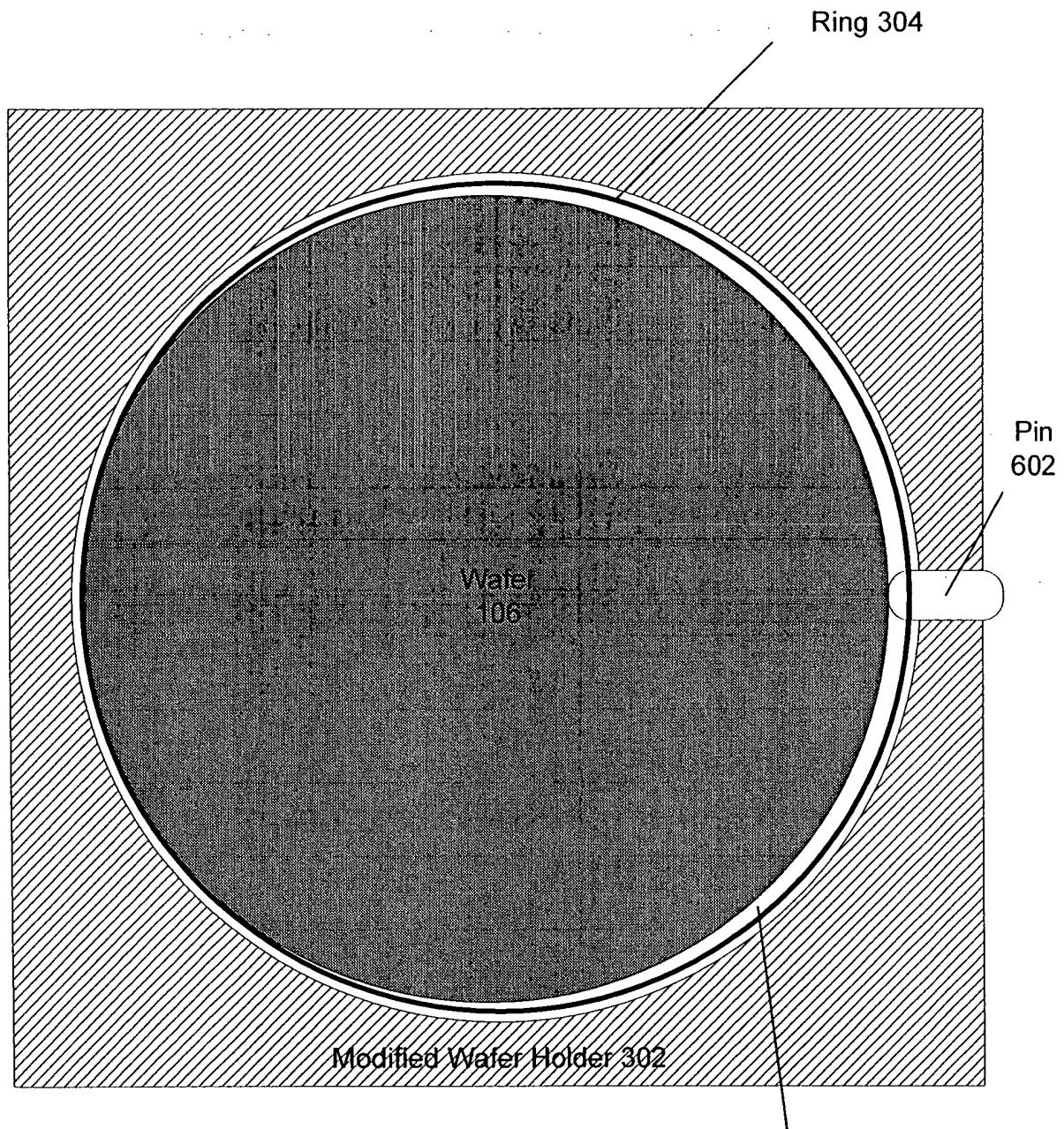


FIG. 6

Predetermined Non-Uniform
Wafer-to-Holder Gap
604

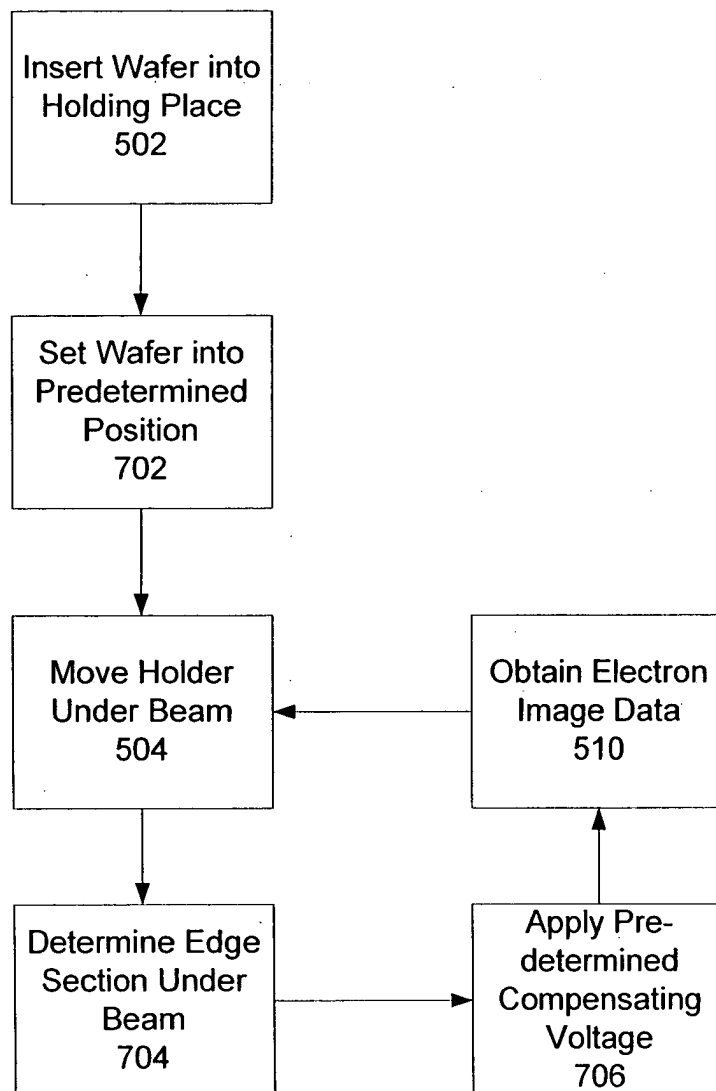


FIG. 7